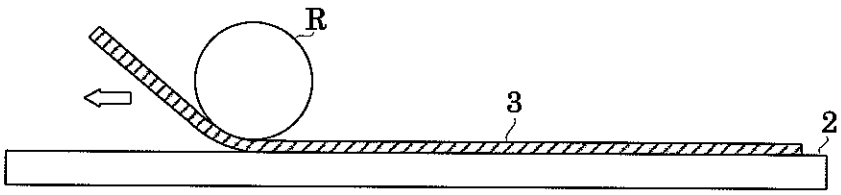
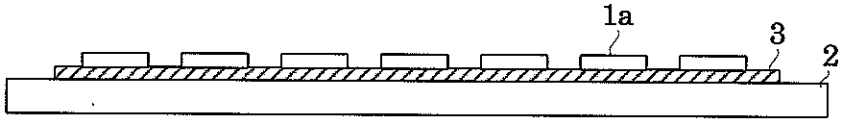
Fig.1 RRIOR ART

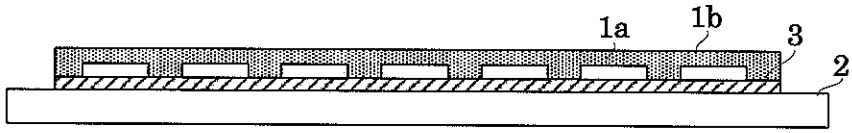
(a)



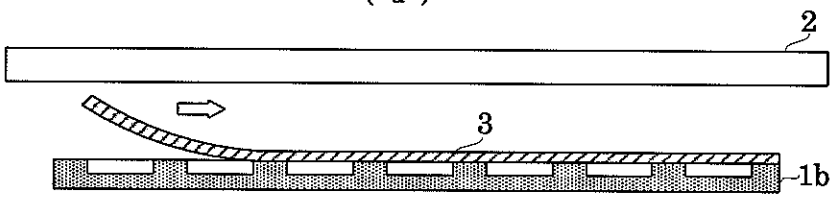
(b)



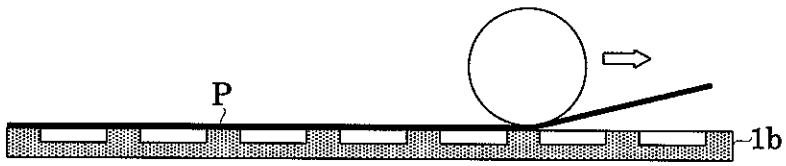
(c)



(d)



(e)



(f)

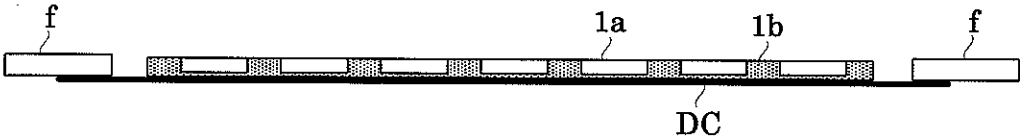


Fig.2

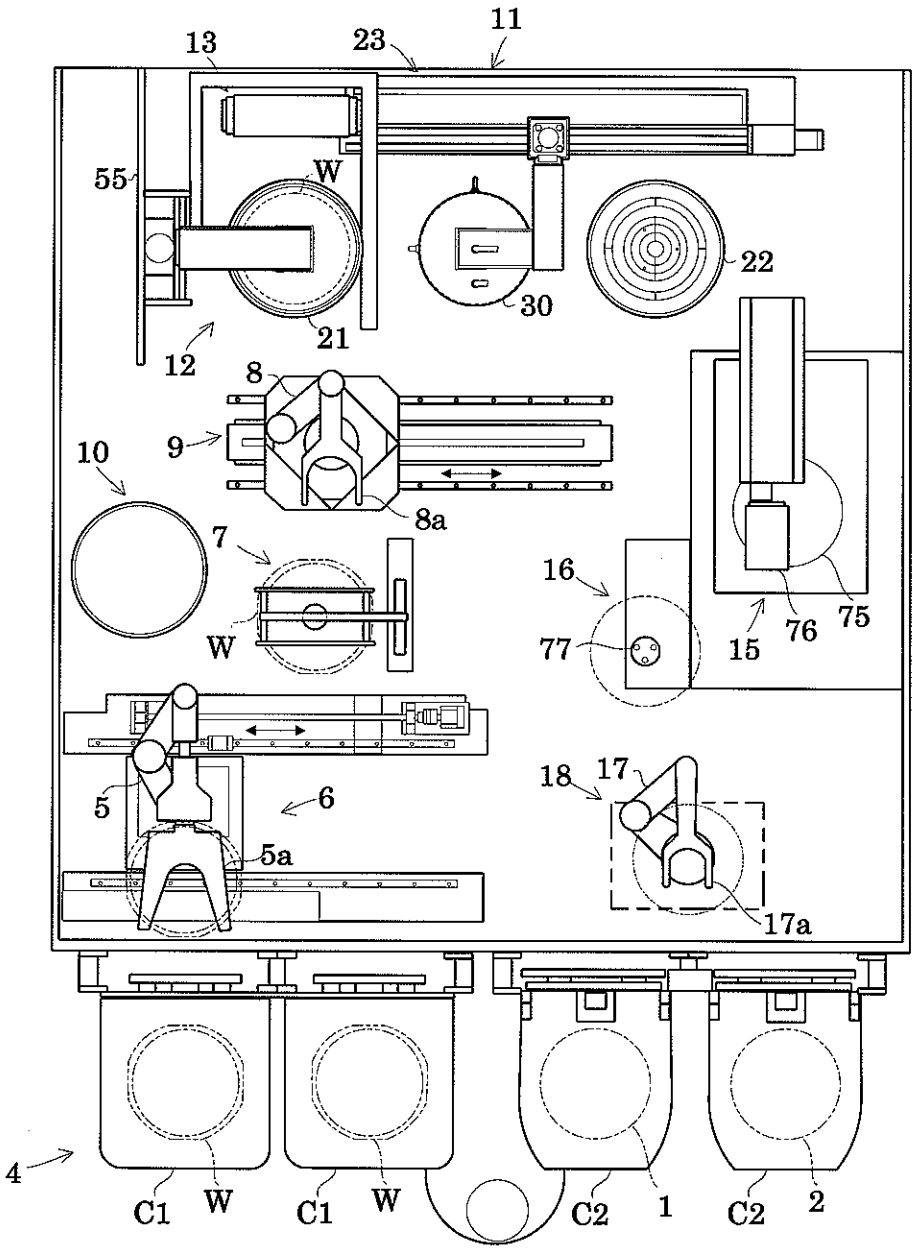

11
13
23
55
W
22
30
21
12
8
9
10
8a
7
W
16
77
15
76
75
5
6
5a
18
17
17a
4
C1
W
C1
W
C2
1
C2
2

Fig.3

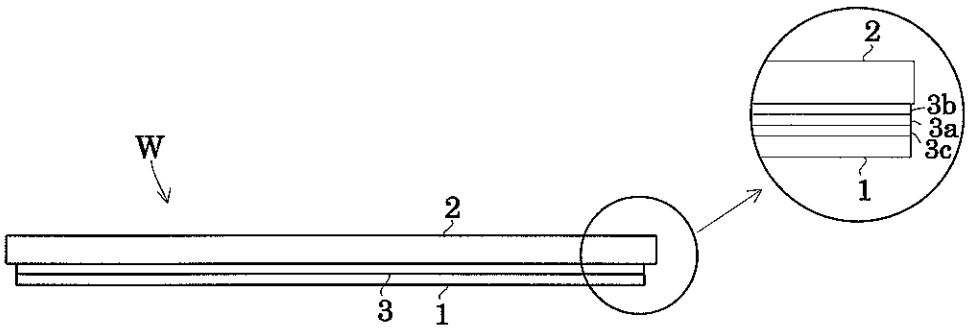


Fig.4

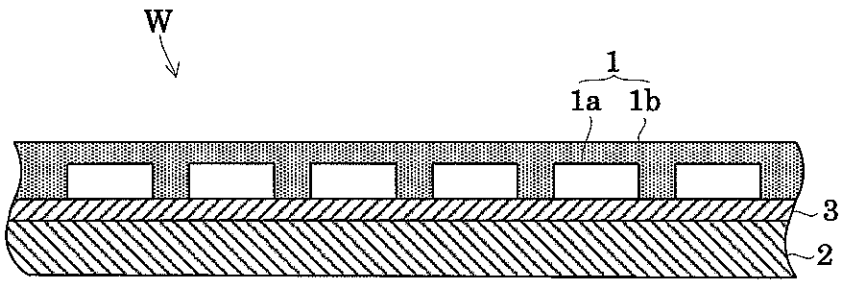


Fig.5

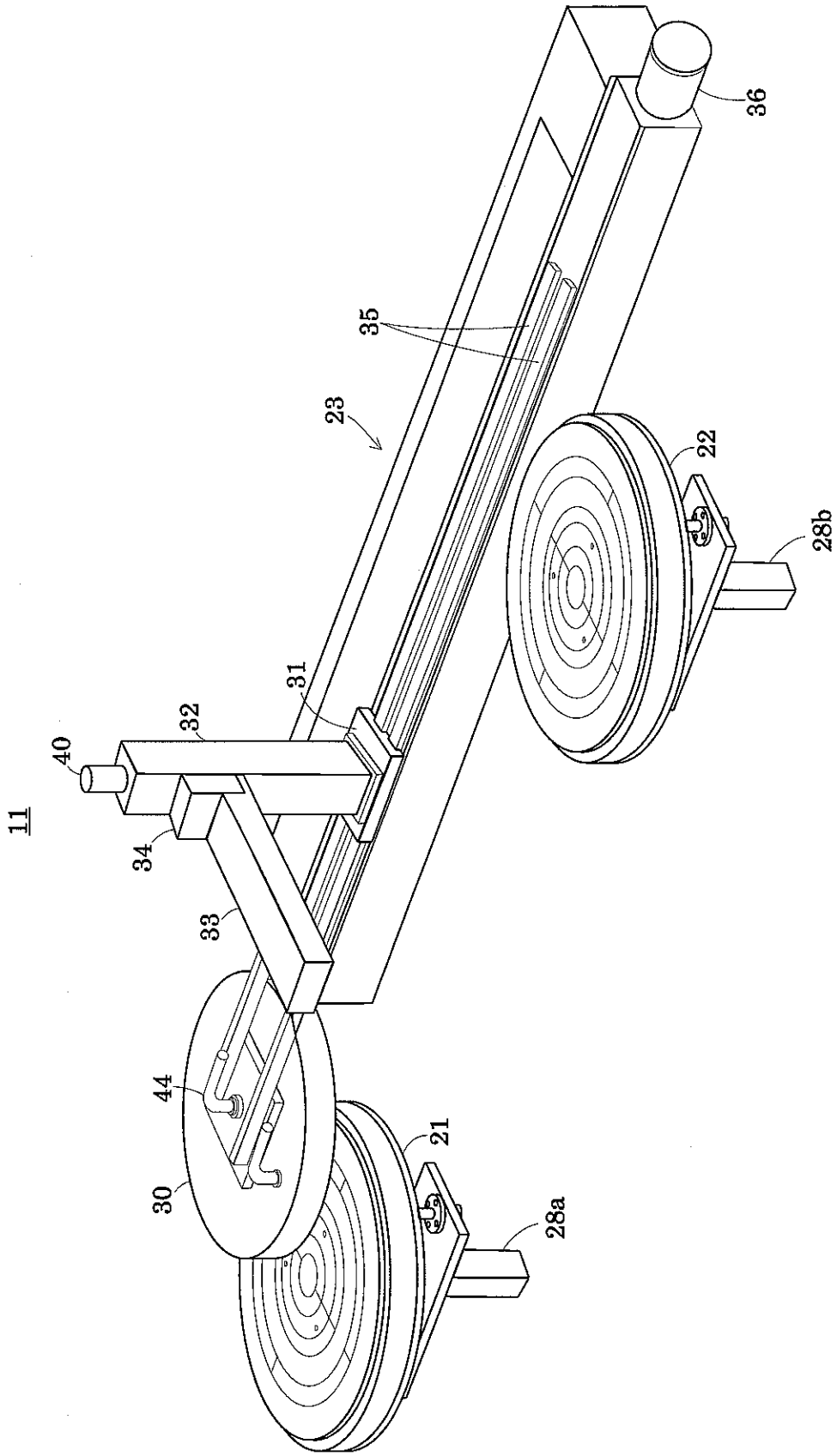


Fig.6

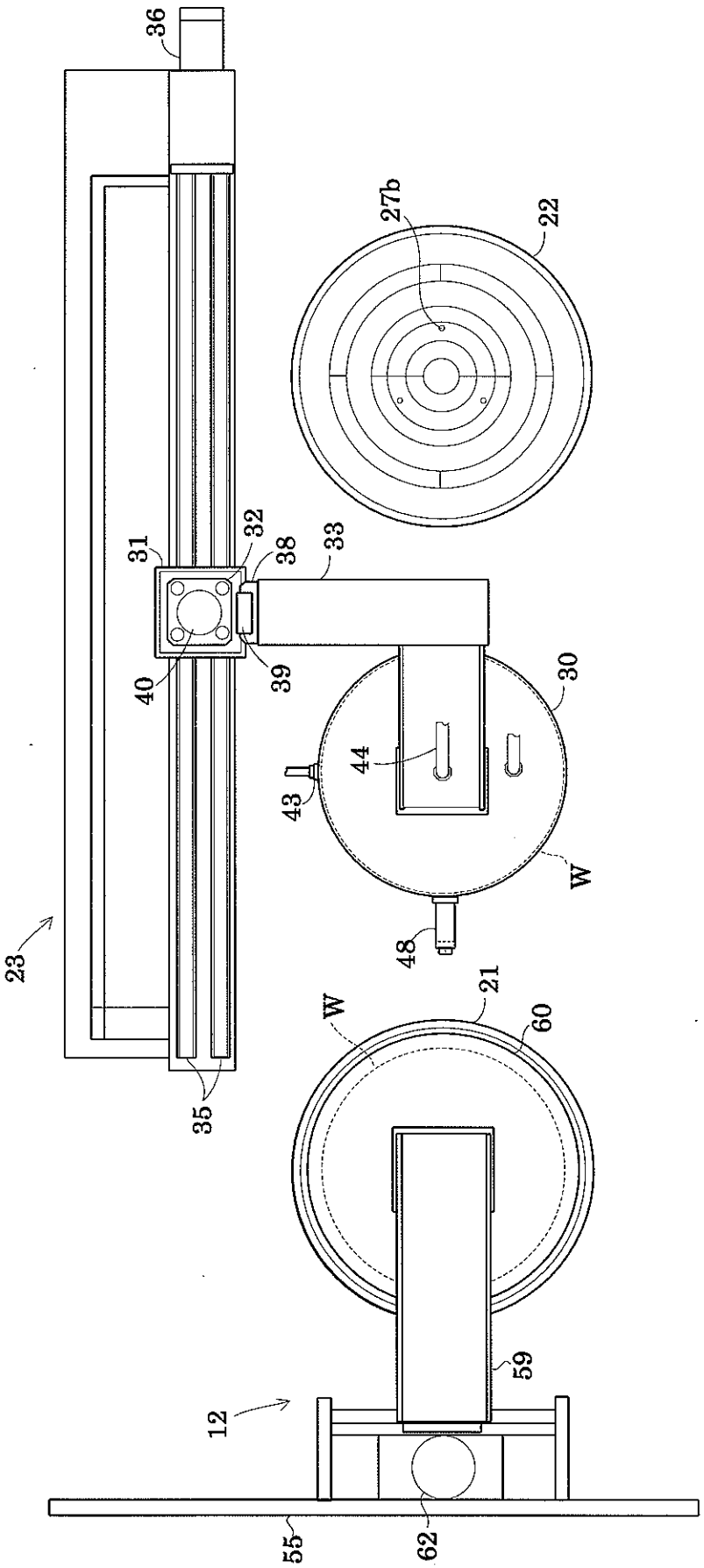


Fig.7

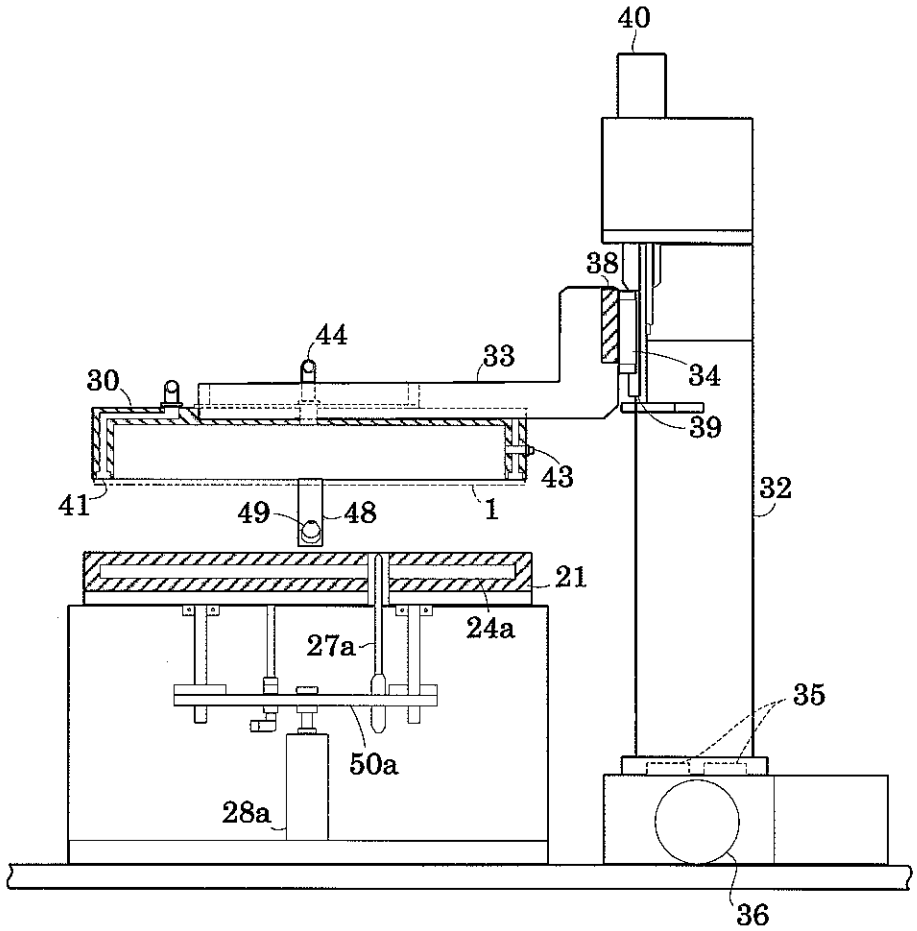


Fig.8

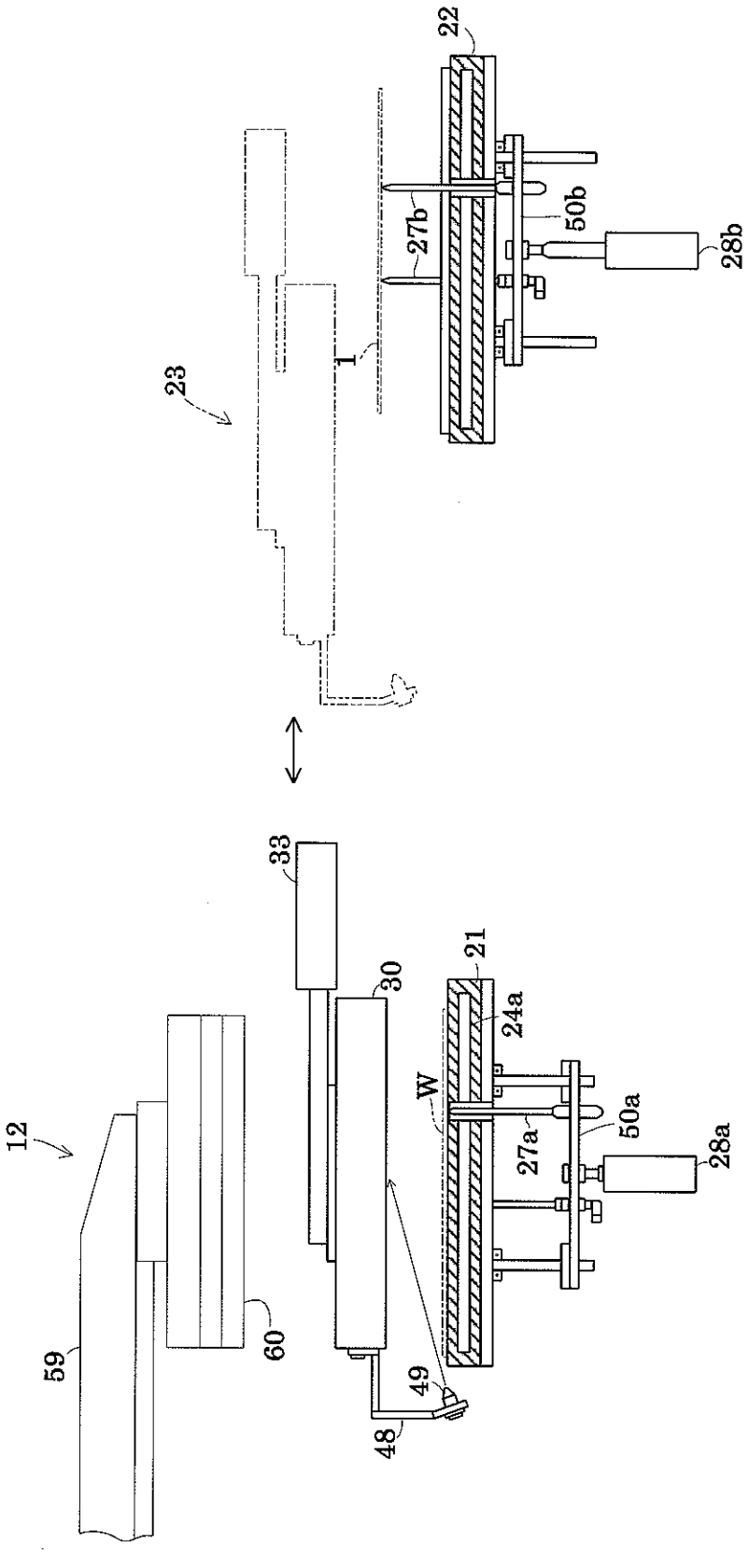


Fig.9

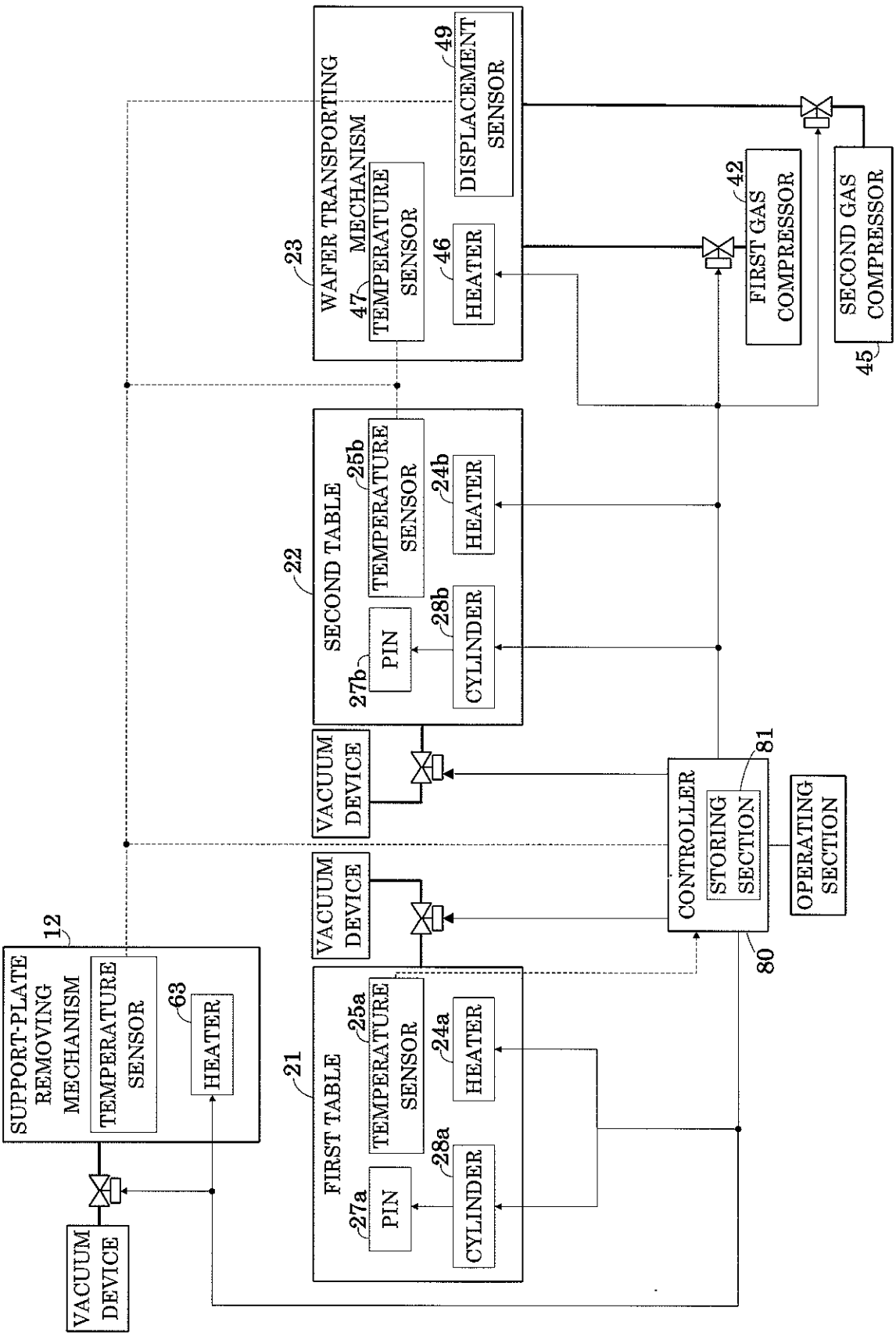

VACUUM DEVICE
SUPPORT-PLATE REMOVING MECHANISM
12
TEMPERATURE SENSOR
63
HEATER
VACUUM DEVICE
FIRST TABLE
21
27a
PIN
28a
CYLINDER
25a
TEMPERATURE SENSOR
24a
HEATER
VACUUM DEVICE
SECOND TABLE
22
27b
PIN
28b
CYLINDER
25b
TEMPERATURE SENSOR
24b
HEATER
WAFER TRANSPORTING MECHANISM
23
47
TEMPERATURE SENSOR
46
HEATER
49
DISPLACEMENT SENSOR
FIRST GAS COMPRESSOR
42
SECOND GAS COMPRESSOR
45
CONTROLLER
80
STORING SECTION
81
OPERATING SECTION

Fig.10

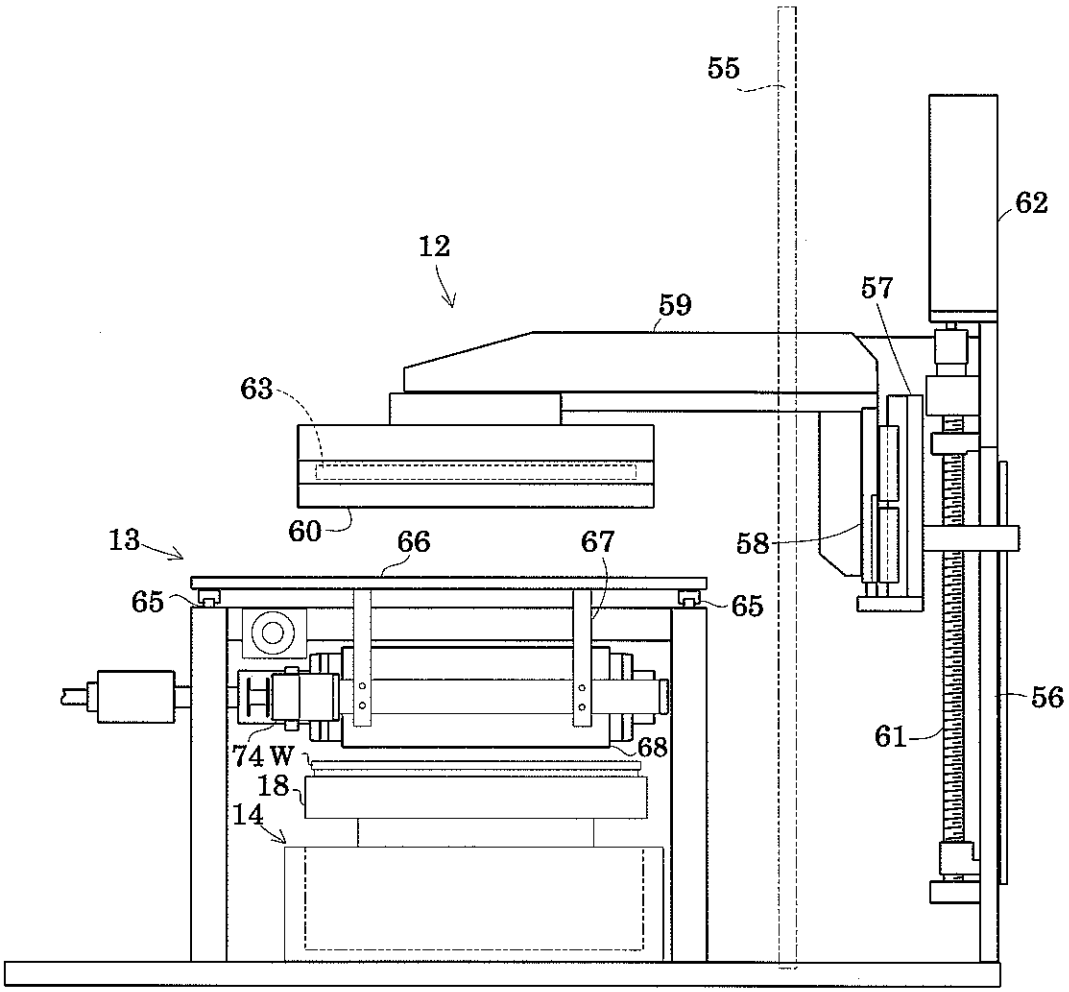


Fig.11

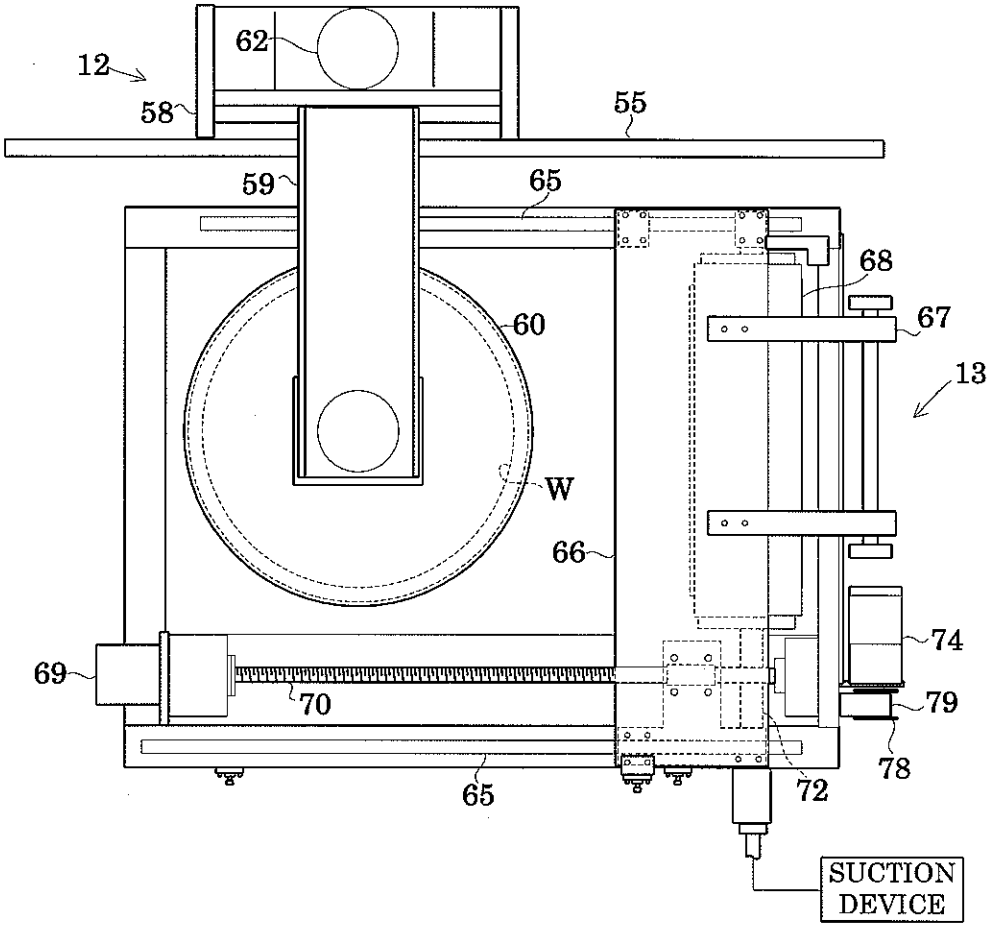

62
12
58
55
59
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68
67
60
13
W
66
74
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70
79
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72
SUCTION DEVICE

Fig.12

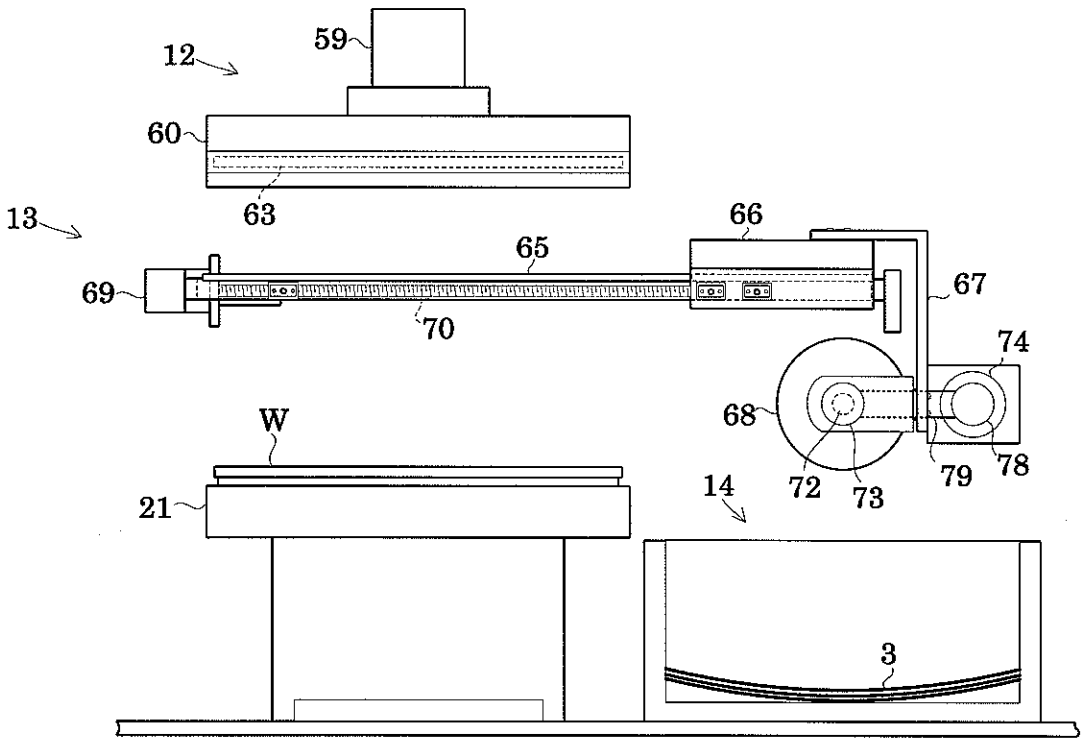

59
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78
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Fig.13

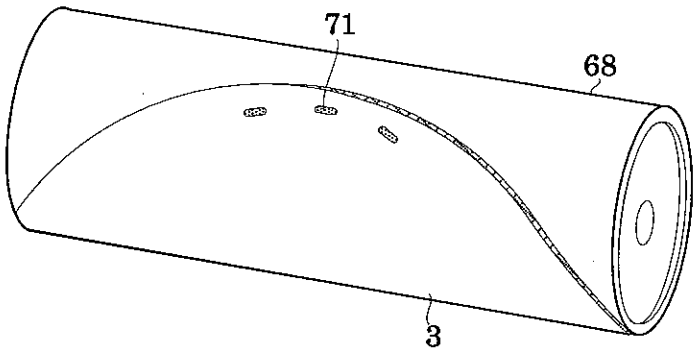


Fig.14

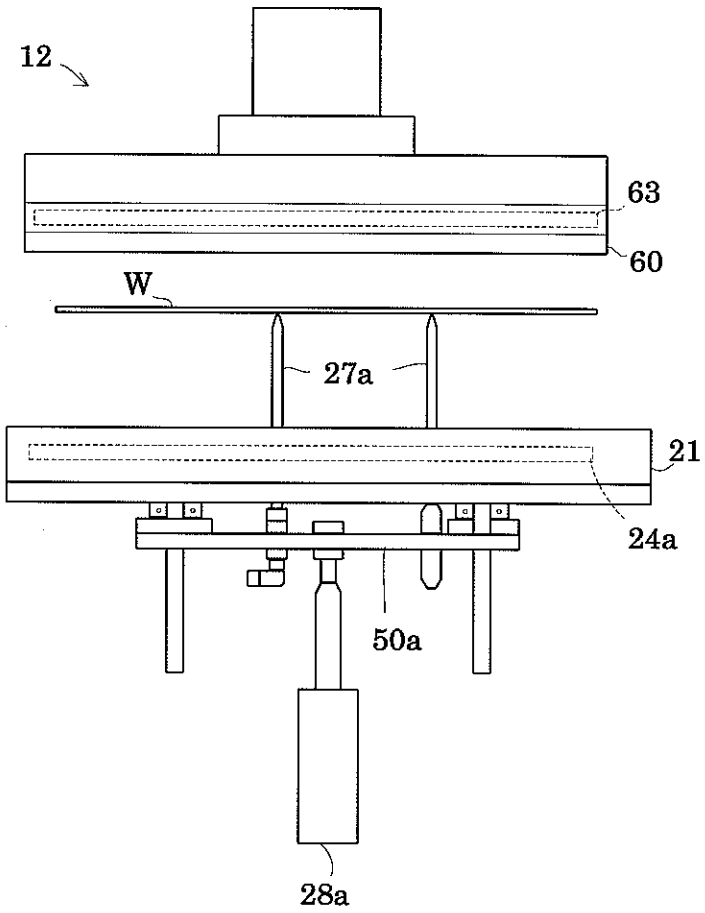


Fig.15

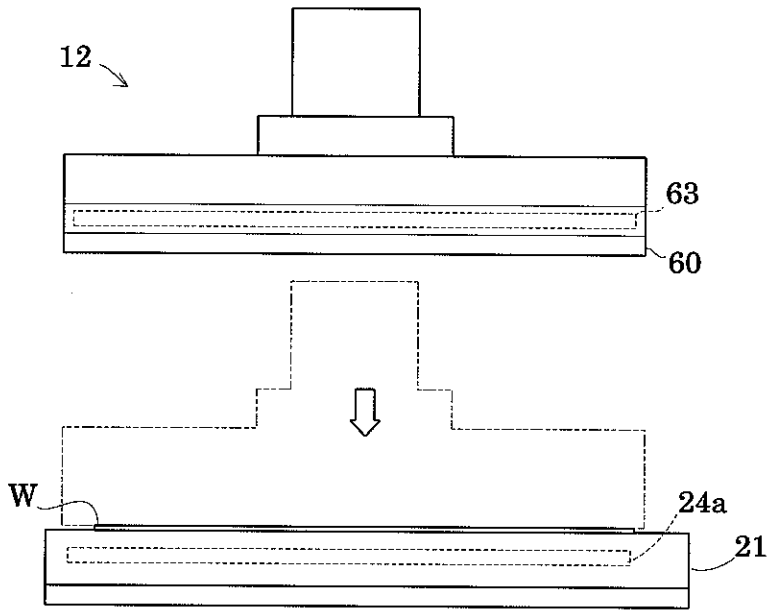


Fig.16

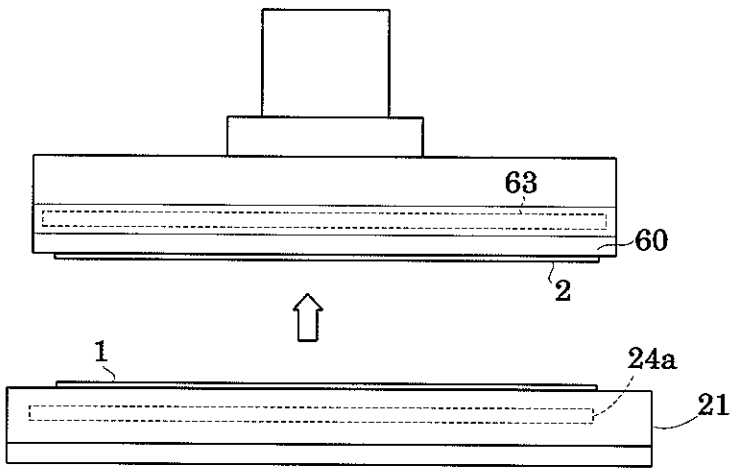


Fig.17

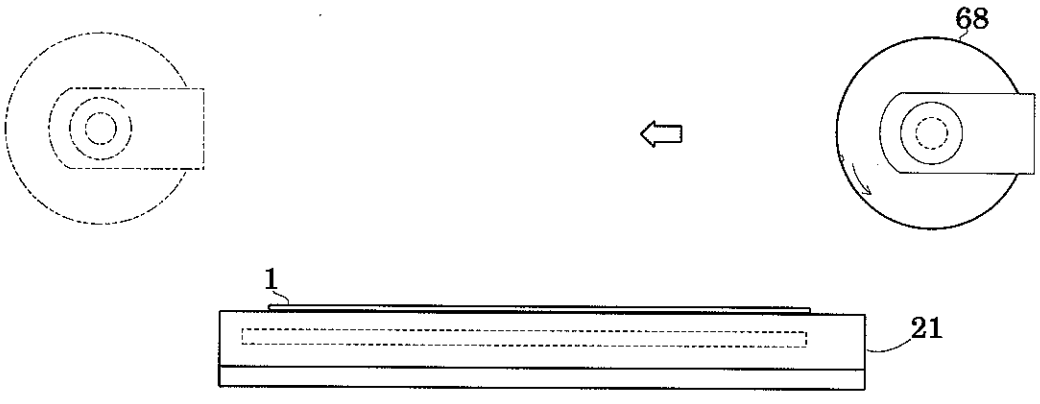


Fig.18

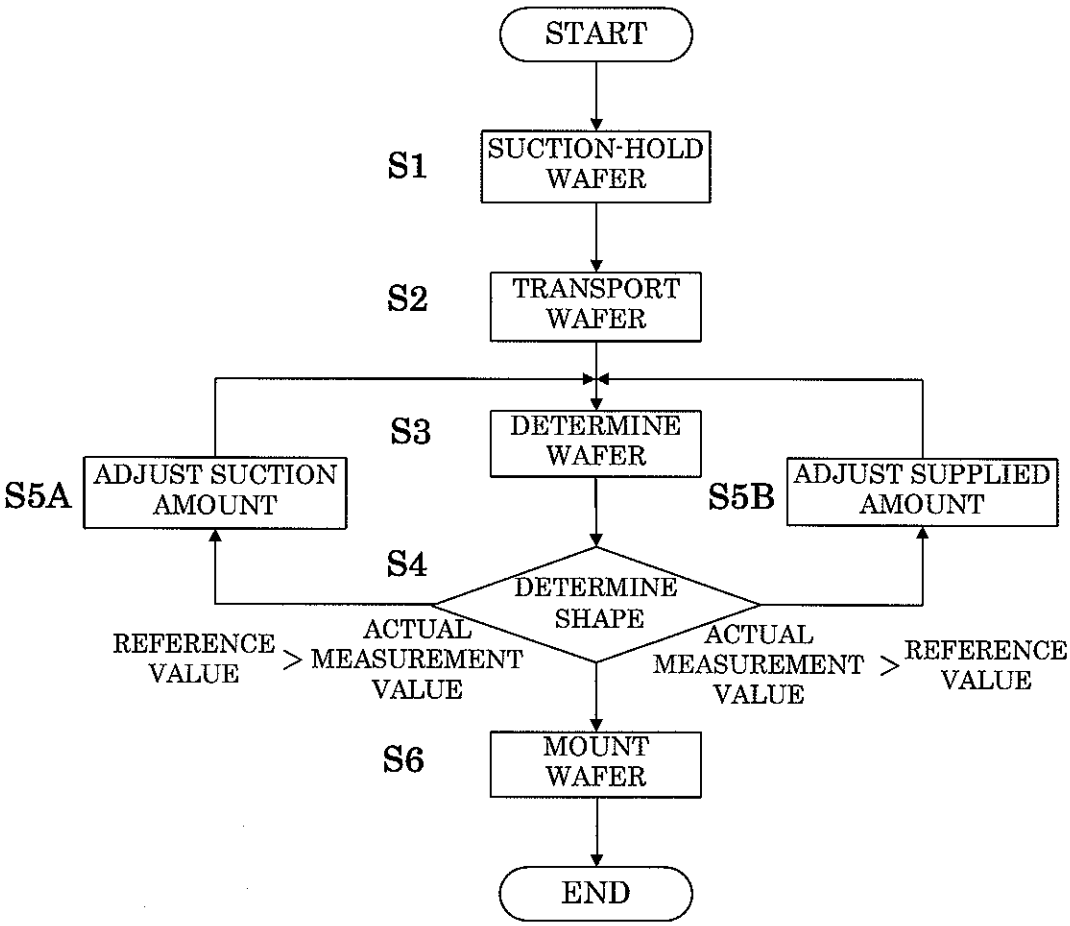

START
S1
SUCTION-HOLD WAFER
S2
TRANSPORT WAFER
S3
DETERMINE WAFER
S5A
ADJUST SUCTION AMOUNT
S5B
ADJUST SUPPLIED AMOUNT
S4
DETERMINE SHAPE
REFERENCE VALUE > ACTUAL MEASUREMENT VALUE
ACTUAL MEASUREMENT VALUE > REFERENCE VALUE
S6
MOUNT WAFER
END

Fig.19

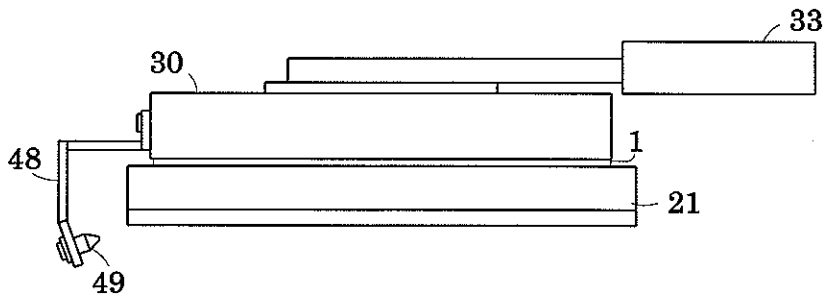

33
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1
48
21
49

Fig.20

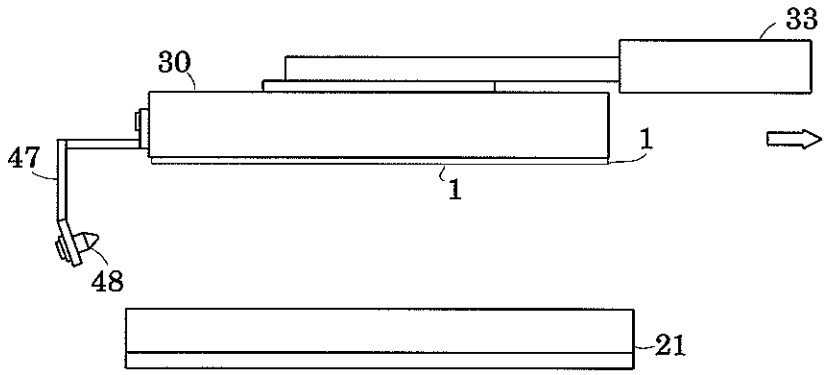


Fig.21

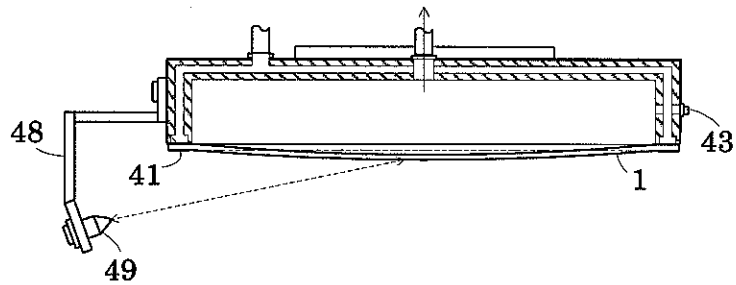


Fig.22

